

Sheet 1 of 1FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
116-010872SERIAL NO.
09/877,223INFORMATION DISCLOSURE STATEMENT
STATEMENT BY APPLICANT

APPLICANT(S)

Kazuhiro HONDA

(Use several sheets if necessary)

FILING DATE
June 8, 2001GROUP ART UNIT
2877

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	AL							
	AM							
	AN							
	AO							
	AP							

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

w7	AQ	"Evaluation of an Advanced Mask Writing System", Shinji KUBO et al., <u>Part of the SPIE Symposium on Photomask and X-Ray Mask Technology VI, Yokohama, Japan, September 1999, SPIE Vol. 3748, pp. 426-435.</u>
w7	AR	"Measuring Critical Dimensions and Overlays as Prescribed by the National Technology Roadmap for Semiconductors", Syed A. Rizvi, <u>SPIE Vol. 3236, pp. 170-175.</u>
w7	AS	"Proximity Effect in Electron-Beam Lithography", T.H.P. Chang, <u>J. Vac. Sci. Technol., Vol. 12, No. 6, Nov./Dec. 1975, pp. 1271-1275.</u>

EXAMINER

DATE CONSIDERED

4-14-04

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.